



RESPONSE UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2851

00862.022434.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
Shinichi SHIMA ) : Examiner: H. Nguyen  
Application No.: 09/986,958 ) : Group Art Unit: 2851  
Filed: November 13, 2001 ) : Confirmation No.: 638  
For: EXPOSURE APPARATUS, METHOD OF ) : October 10, 2003  
MANUFACTURING SEMICONDUCTOR )  
DEVICES, SEMICONDUCTOR MANUFACTURING )  
PLANT, METHOD OF MAINTAINING EXPOSURE :  
APPARATUS, AND POSITION DETECTOR )

TECHNOLOGY CENTER 2800

OCT 15 2003

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION AND LETTER  
FORWARDING SUBSTITUTE SPECIFICATION

Sir:

In response to the Official Action dated July 11, 2003, please amend the above-identified  
application as follows: